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			3. First silicon experiments within wafers Heavlin, W.D.; Semiconductor Manufacturing Conference Proceedings, 1999 IEEE Internation 11-13 Oct. 1999 Page(s):375 - 378	onal Symp			
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			4. Intrafield effects and device manufacturability: a statistical simulation a Krivokapic, Z.; Minvielle, A.; Heavlin, W.D.; Statistical Metrology, 1998. 3rd International Workshop on 7 June 1998 Page(s):36 - 39	pproach			
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AbstractPlus | References | Full Text: PDF(1184 KB) | IEEE JNL

8. Parametric manufacturing yield modeling of GaAs/AlGaAs multiple quantum with photodiodes Ilgu Yun; May, G.S.; Semiconductor Manufacturing, IEEE Transactions on Volume 12, Issue 2, May 1999 Page(s):238 - 251 AbstractPlus References Full Text: PDF(432 KB) IEEE JNL. 9. Thin film transistors for foldable displays Ma, E.Y.; Theiss, S.D.; Lu, M.H.; Wu, C.C.; Sturn, J.C.; Wagner, S.; Electron Devices Meeting, 1997. Technical Digest., International 7-10 Dec. 1997 Page(s):535 - 538 AbstractPlus Full Text: PDF(260 KB) IEEE CNF 10. DGPS/INS integrated positioning for control of automated vehicle Redmill, K.A.; Kitajima, T.; Ozguner, U.; Intelligent Transportation Systems, 2001. Proceedings. 2001 IEEE 25-29 Aug. 2001 Page(s):172 - 178 AbstractPlus Full Text: PDF(592 KB) IEEE CNF		 Crosstalk and microlens study in a color CMOS image sensor Agranov, G.; Berezin, V.; Tsai, R.H.; Electron Devices, IEEE Transactions on Volume 50, Issue 1, Jan. 2003 Page(s):4 - 11
photodiodes Ilgu Yun; May, G.S.; Semiconductor Manufacturing, IEEE Transactions on Volume 12, Issue 2, May 1999 Page(s):238 - 251 AbstractPlus References Full Text: PDF(432 KB) IEEE JNL 9. Thin film transistors for foldable displays Ma, E.Y.; Theiss, S.D.; Lu, M.H.; Wu, C.C.; Sturn, J.C.; Wagner, S.; Electron Devices Meeting, 1997. Technical Digest., International 7-10 Dec. 1997 Page(s):535 - 538 AbstractPlus Full Text: PDF(260 KB) IEEE CNF 10. DGPS/INS integrated positioning for control of automated vehicle Redmill, K.A.; Kitajima, T.; Ozguner, U.; Intelligent Transportation Systems, 2001. Proceedings. 2001 IEEE 25-29 Aug. 2001 Page(s):172 - 178		AbstractPlus References Full Text: PDF(1666 KB) IEEE JNL
 9. Thin film transistors for foldable displays Ma, E.Y.; Theiss, S.D.; Lu, M.H.; Wu, C.C.; Sturn, J.C.; Wagner, S.; Electron Devices Meeting, 1997. Technical Digest., International 7-10 Dec. 1997 Page(s):535 - 538 AbstractPlus Full Text: PDF(260 KB) IEEE CNF 10. DGPS/INS integrated positioning for control of automated vehicle Redmill, K.A.; Kitajima, T.; Ozguner, U.; Intelligent Transportation Systems, 2001. Proceedings. 2001 IEEE 25-29 Aug. 2001 Page(s):172 - 178 		Ilgu Yun; May, G.S.; Semiconductor Manufacturing, IEEE Transactions on
Ma, E.Y.; Theiss, S.D.; Lu, M.H.; Wu, C.C.; Sturn, J.C.; Wagner, S.; Electron Devices Meeting, 1997. Technical Digest., International 7-10 Dec. 1997 Page(s):535 - 538 AbstractPlus Full Text: PDF(260 KB) IEEE CNF 10. DGPS/INS integrated positioning for control of automated vehicle Redmill, K.A.; Kitajima, T.; Ozguner, U.; Intelligent Transportation Systems, 2001. Proceedings. 2001 IEEE 25-29 Aug. 2001 Page(s):172 - 178		AbstractPlus References Full Text: PDF(432 KB) IEEE JNL
10. DGPS/INS integrated positioning for control of automated vehicle Redmill, K.A.; Kitajima, T.; Ozguner, U.; Intelligent Transportation Systems, 2001. Proceedings. 2001 IEEE 25-29 Aug. 2001 Page(s):172 - 178		Ma, E.Y.; Theiss, S.D.; Lu, M.H.; Wu, C.C.; Sturn, J.C.; Wagner, S.; Electron Devices Meeting, 1997. Technical Digest., International
Redmill, K.A.; Kitajima, T.; Ozguner, U.; Intelligent Transportation Systems, 2001. Proceedings. 2001 IEEE 25-29 Aug. 2001 Page(s):172 - 178		AbstractPlus Full Text: PDF (260 KB) IEEE CNF
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5	INZZ	heavlin-w\$	unrestricted	12	show titles
6	INZZ	heavlin-w\$ AND semiconductor	unrestricted	8	show titles
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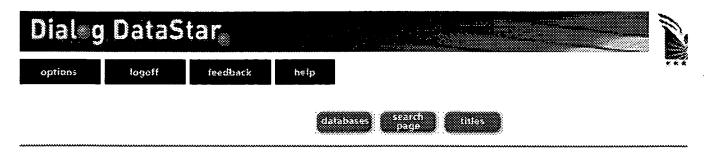
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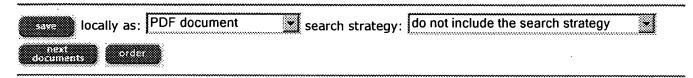
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document 1 of 2 Order Document

INSPEC - 1969 to date (INZZ)

Accession number & update

6239912, B1999-06-2570-009; 19990501.

Title

Enhancing fab performance under team council methodology.

Author(s)

<u>Dupuis-R-N-Jr</u>; <u>Gervais-J</u>; <u>Park-S</u>.

Author affiliation

Fairchild Semicond, South Portland, ME, USA.

Source

IEEE/SEMI. 1998 IEEE/SEMI Advanced **Semiconductor Manufacturing** Conference and Workshop, Boston, MA, USA, 23-25 Sept. 1998.

Sponsors: Semicond. Equipment & Mater. Int. (SEMI), IEEE, IEEE Electron Devices Soc., IEEE Components, Packaging & Manuf. Technol. Soc.

In: p.119-21, 1998.

ISSN

ISBN: 0-7803-4380-8, CCCC: 0 7803 4380 8/98/ (\$10.00).

Publication year

1998.

Language

EN.

Publication type

CPP Conference Paper.

Treatment codes

P Practical.

Abstract

The objective of this paper is to outline and describe the process of developing team councils in a wafer fab organization. Initially, we present the historical background and why we thought this type of approach was necessary to achieve high performance from all levels of the organization. A road **map** to success as well as a task level migration **matrix** describes the different levels of responsibility needed to achieve the results described in the conclusion of this paper. Though this process is still evolving and developing in the authors' South Portland fab, the paper describes the necessary steps to implement this process. (3 refs).

Descriptors

<u>computer-integrated-manufacturing</u>; <u>integrated-circuit-reliability</u>; <u>integrated-circuit-technology</u>; <u>integrated-circuit-yield</u>; <u>management</u>; <u>manufacturing-resources-planning</u>; <u>training</u>.

Keywords

wafer fab performance; team council methodology; wafer fab organization; team councils; road map; task level migration matrix; responsibility levels; process implementation; training; CIM.

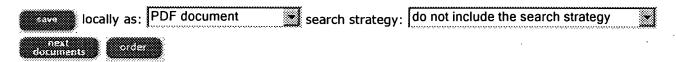
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B0170N	(Reliability).
B0140	(Administration and management).
B0120	(Education and training).

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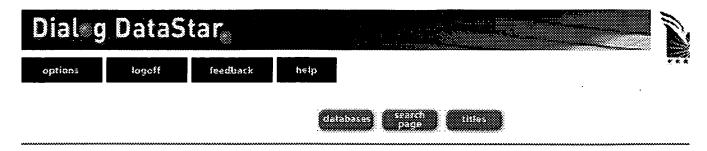
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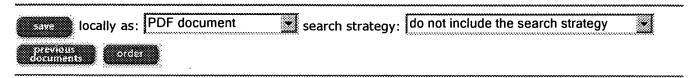
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document 2 of 2 Order Document

INSPEC - 1969 to date (INZZ)

Accession number & update

4275011, C9212-7480-045; 921104.

Title

Semi-conductor integrated technical data manager.

Author(s)

Gagliardi-D-J; Kleinman-Y-N.

Author affiliation

IBM, Hopewell Jct, NY, USA.

Source

Eleventh IEEE/CHMT International Electronics Manufacturing Technology Symposium (Cat.

No.91CH3043-7), San Francisco, CA, USA, 16-18 Sept. 1991, p.222-5.

Sponsors: IEEE.

Published: IEEE, New York, NY, USA, 1991, xvi+449 pp.

ISSN

ISBN: 0-7803-0155-2, CCCC: CH3043-7/91/0000-0222 (\$01.00).

Publication year

1991.

Language

EN.

Publication type

CPP Conference Paper.

Treatment codes

P Practical.

Abstract

The author describes the architecture of the Semi-Conductor Integrated Technical Data Manager (SCIM) system. SCIM is a design automation system that integrates data and controls the processes that are required for the release of the masterslice to **manufacturing**. The two key components of the system are the relational database and its functional controller. As the data are generated by the design community, the relational database allows for the integration of all independent data elements across the design life cycle. The functional controller ensures the integrity of the process and that it is in compliance with the ground-rule specifications. In particular, the authors address the creation and integration of the product **matrix**, the wafer **map** (or stepping plan), and the technology ground rules, which are all central to the release of masterslice design data to **manufacturing**. (3 refs).

Descriptors

<u>CAD-CAM</u>; <u>integrated-circuit-manufacture</u>; <u>process-computer-control</u>; <u>relational-databases</u>; <u>semiconductor-device-manufacture</u>.

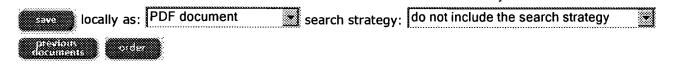
Keywords

Semi Conductor Integrated Technical Data Manager; SCIM; design automation system; masterslice; relational database; functional controller; product matrix; wafer map; stepping plan; technology

Classification codes

C7480	(Production engineering).
C3355Z	(Other manufacturing processes).
C7420	(Control engineering).
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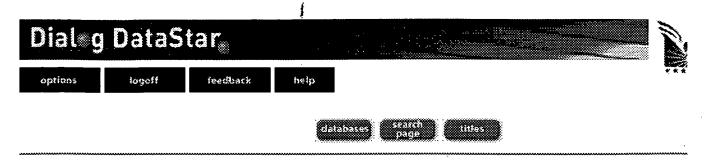
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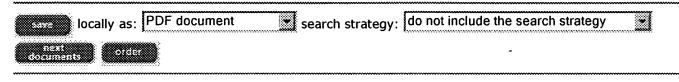
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INSPEC - 1969 to date (INZZ)

Accession number & update

7820829, B2004-02-2560-002; 20040101.

Title

Designing experiments for causal networks.

Author(s)

Heavlin-W-D.

Author affiliation

Adv Micro Devices, Granada, Spain.

Source

Technometrics (USA), vol.45, no.2, p.115-29, May 2003. , Published: American Soc. Quality Control; American Stat. Assoc.

CODEN

TCMTA2.

ISSN

ISSN: 0040-1706.

Availability

SICI: 0040-1706(200305)45:2L.115:DECN; 1-F.

Publication year

2003.

Language

EN.

Publication type

J Journal Paper.

Treatment codes

A Application.

Abstract

Causal networks are directed graphs representing cause-effect relationships and are multiple-response generalizations of Ishikawa's cause-effect diagrams. Emphasizing tolerance design applications, this article describes an algorithm for designing suitable experiments when the factors and responses are organized as a causal network. The causal network is transformed into a so-called causal map, which represents all factors and responses as points in a common D-dimensional metric space. The design approach is algorithmic, optimizing the entropy criterion due to Wynn. This criterion is applied to maximize dispersion among the multiple responses, using a distance-in-space coefficients model. A key constraint is for the blocks to be self-contained; this implies that each block can be analyzed without

reference to other blocks. This is to be complemented by a unified, all-block analysis. The resulting designs are evaluated for efficiency, response dispersion, and resolution V column rank. Particular attention is given to skewing each block by shifting one or a few factors off-center. (22 refs).

Descriptors

causality; cause-effect-analysis; process-control; semiconductor-device-manufacture.

Keywords

causal networks; directed graphs; cause effect relationships; multiple response generalizations; Ishikawa s cause effect diagrams; tolerance design applications; common D dimensional metric space; multiple responses; distance in space coefficients model; efficiency; response dispersion.

Classification codes

B2560 (Semiconductor devices).

B0170E (Production facilities and engineering).

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L1: Entry 1 of 12 File: PGPB Jan 16, 2003

PGPUB-DOCUMENT-NUMBER: 20030014144

PGPUB-FILING-TYPE: new

DOCUMENT-IDENTIFIER: US 20030014144 A1

TITLE: FEED-FORWARD CONTROL OF TCI DOPING FOR IMPROVING MASS-PRODUCTION-WISE, STATISTICAL DISTRIBUTION OF CRITICAL PERFORMANCE PARAMETERS IN SEMICONDUCTOR

DEVICES

PUBLICATION-DATE: January 16, 2003

INVENTOR-INFORMATION:

NAME CITY COUNTRY STATE RULE-47

Krivokapic, Zoran Santa Clara CA US US

<u>Heavlin</u>, William D. El Granada CA

US-CL-CURRENT: 700/121; 700/44

Full Title Citation Front Review Classification Date Reference Sequences Attachments Claims Kill Draw De

2. Document ID: US 6708073 B1

L1: Entry 2 of 12 File: USPT Mar 16, 2004

US-PAT-NO: 6708073

DOCUMENT-IDENTIFIER: US 6708073 B1

TITLE: Lot specific process design methodology

DATE-ISSUED: March 16, 2004

INVENTOR-INFORMATION:

NAME CITY STATE ZIP CODE COUNTRY

Heavlin; William D. El Granada

US-CL-CURRENT: 700/121; 700/31

Full Title Citation Front Review Classification Date Reference Claims KMC Draw De 3. Document ID: US 6586755 B1

L1: Entry 3 of 12

File: USPT

Jul 1, 2003

US-PAT-NO: 6586755

DOCUMENT-IDENTIFIER: US 6586755 B1

TITLE: Feed-forward control of TCI doping for improving mass-production-wise statistical distribution of critical performance parameters in semiconductor

devices

DATE-ISSUED: July 1, 2003

INVENTOR-INFORMATION:

NAME

CITY

STATE ZIP CODE

COUNTRY

Krivokapic; Zoran

Santa Clara

CA

<u>Heavlin</u>; William D.

El Granada

CA

US-CL-CURRENT: <u>250/492.21</u>; <u>250/492.23</u>, <u>257/E21.525</u>, <u>438/5</u>, <u>438/7</u>

4. Document ID: US 6567717 B2

L1: Entry 4 of 12

File: USPT

May 20, 2003

US-PAT-NO: 6567717

DOCUMENT-IDENTIFIER: US 6567717 B2

TITLE: Feed-forward control of TCI doping for improving mass-production-wise, statistical distribution of critical performance parameters in semiconductor

devices

DATE-ISSUED: May 20, 2003

INVENTOR-INFORMATION:

<u>Heavlin</u>; William D.

NAME

CITY

STATE

ZIP CODE COUNTRY

Krivokapic; Zoran

Santa Clara El Granada CA

CA

US-CL-CURRENT: <u>700/121</u>; <u>438/14</u>

Full | Title | Citation | Front | Review | Classification | Date | Reference | Claims | Claims | KMC | Draw De

5. Document ID: US 6389366 B1

L1: Entry 5 of 12

File: USPT

May 14, 2002

US-PAT-NO: 6389366

DOCUMENT-IDENTIFIER: US 6389366 B1

TITLE: Methods for identifying sources of patterns in processing effects in

manufacturing

DATE-ISSUED: May 14, 2002

INVENTOR-INFORMATION:

NAME

CITY

STATE ZIP CODE

COUNTRY

Heavlin; William D.

El Granada

CA

US-CL-CURRENT: 702/84; 438/21, 700/117, 702/81

Full Title Citation Front	Review Classification D.	ate Reference	Claims KWMC Draw De

6. Document ID: US 6366822 B1

L1: Entry 6 of 12

File: USPT

Apr 2, 2002

US-PAT-NO: 6366822

DOCUMENT-IDENTIFIER: US 6366822 B1

TITLE: Statistical process window design methodology

DATE-ISSUED: April 2, 2002

INVENTOR-INFORMATION:

NAME

CITY

STATE ZIP CODE

COUNTRY

<u>Heavlin</u>; William D.

El Granada

CA

US-CL-CURRENT: 700/31; 700/121

•		•	
Full Title Citation Front			Claims KWC Draw De
		•	- 12 - 13/ 20 - 13
	***************************************	***************************************	***************************************

7. Document ID: US 6304836 B1

L1: Entry 7 of 12

File: USPT

Oct 16, 2001

US-PAT-NO: 6304836

DOCUMENT-IDENTIFIER: US 6304836 B1

** See image for <u>Certificate of Correction</u> **

TITLE: Worst case design parameter extraction for logic technologies

DATE-ISSUED: October 16, 2001

INVENTOR-INFORMATION:

NAME

CITY Santa Clara

STATE ZIP CODE

COUNTRY

Krivokapic; Zoran

Heavlin; William D. El Granada

CA

CA

US-CL-CURRENT: <u>703/14</u>; <u>703/13</u>

Record List Display Page 4 of 6

Full Title Citation Front Review Classification Date Reference Claims KMC Draw D.

8. Document ID: US 5966527 A

L1: Entry 8 of 12

File: USPT

Oct 12, 1999

US-PAT-NO: 5966527

DOCUMENT-IDENTIFIER: US 5966527 A

TITLE: Apparatus, article of manufacture, method and system for simulating a mass-

produced semiconductor device behavior

DATE-ISSUED: October 12, 1999

INVENTOR-INFORMATION:

NAME

CITY

STATE ZIP CODE

COUNTRY

Krivokapic; Zoran
Heavlin; William D.

Santa Clara San Francisco CA

o CA

US-CL-CURRENT: 703/14

	Full	Title	Citation Fro	ont Review	Classification	Date	Reference		C la ims	KWIC	Drawa De
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	<b>m</b>	9	Document 1	D. US 59.	46214 A						

9. Document ID: US 5946214 A

L1: Entry 9 of 12

File: USPT

Aug 31, 1999

US-PAT-NO: 5946214

DOCUMENT-IDENTIFIER: US 5946214 A

TITLE: Computer implemented method for estimating fabrication yield for

semiconductor integrated circuit including memory blocks with redundant rows and/or

columns

DATE-ISSUED: August 31, 1999

INVENTOR-INFORMATION:

NAME CI'

CITY

STATE ZIP CODE

COUNTRY

Heavlin; William D.

San Francisco

CA

Kittler; Richard C.

Sunnyaale

CA

Wen; Ping

Sunnyvale .

CA

US-CL-CURRENT: 700/121; 365/200, 365/201, 700/95, 700/96

Full Title Citation Front Review Classification Date Reference Citation Claims KMC Draw De

10. Document ID: US 5724251 A

L1: Entry 10 of 12

File: USPT

Mar 3, 1998

US-PAT-NO: 5724251

DOCUMENT-IDENTIFIER: US 5724251 A

TITLE: System and method for designing, fabricating and testing multiple cell test

structures to validate a cell library

DATE-ISSUED: March 3, 1998

INVENTOR-INFORMATION:

NAME CITY STATE ZIP CODE COUNTRY

Heavlin; William D. San Francisco CA

US-CL-CURRENT: <u>716/5</u>; <u>716/11</u>

# Full Title Citation Front Review Classification Date Reference Claims KMC Draw De

# 11. Document ID: US 5655110 A

L1: Entry 11 of 12

File: USPT

Aug 5, 1997

US-PAT-NO: 5655110

DOCUMENT-IDENTIFIER: US 5655110 A

** See image for <u>Certificate of Correction</u> **

TITLE: Method for setting and adjusting process parameters to maintain acceptable critical dimensions across each die of mass-produced semiconductor wafers

DATE-ISSUED: August 5, 1997

INVENTOR-INFORMATION:

NAME CITY STATE ZIP CODE COUNTRY

Krivokapic; Zoran Santa Clara CA Heavlin; William D. San Francisco CA CA

Kyser; David F. San Jose

US-CL-CURRENT: 716/19; 700/95, 703/13

Full	Title	Citation	Front	Review	Classification	Date	Reference		Claims	K080C	Draw De
								·			

## 12. Document ID: US 5646870 A

L1: Entry 12 of 12

File: USPT

Jul 8, 1997

US-PAT-NO: 5646870

DOCUMENT-IDENTIFIER: US 5646870 A

### ** See image for <u>Certificate of Correction</u> **

TITLE: Method for setting and adjusting process parameters to maintain acceptable critical dimensions across each die of mass-produced semiconductor wafers

DATE-ISSUED: July 8, 1997

INVENTOR-INFORMATION:

NAME

CITY

ZIP CODE STATE

COUNTRY

Krivokapic; Zoran

Santa Clara

CA

Heavlin; William D.

. San Francisco

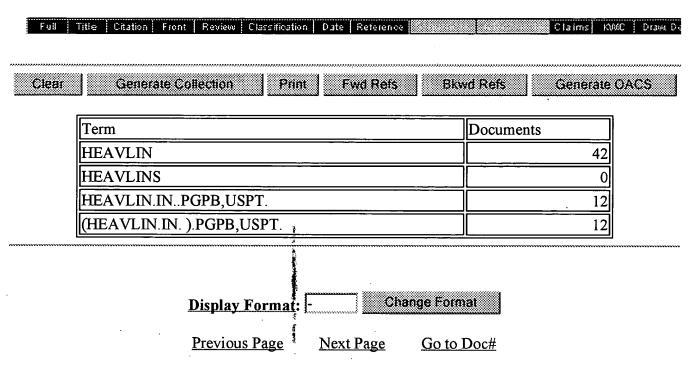
CA

Kyser; David F.

San Jose

CA

US-CL-CURRENT: 716/4; 700/117, 700/31, 703/13, 716/20



# **Hit List**

Clear Generate Collection Print Fwd Refs Bkwd Refs
Generate OACS

Search Results - Record(s) 1 through 2 of 2 returned.

1. Document ID: US 20040064438 A1

L2: Entry 1 of 2

File: PGPB

Apr 1, 2004

PGPUB-DOCUMENT-NUMBER: 20040064438

PGPUB-FILING-TYPE: new

DOCUMENT-IDENTIFIER: US 20040064438 A1

TITLE: Method for data and text mining and literature-based discovery

PUBLICATION-DATE: April 1, 2004

INVENTOR-INFORMATION:

NAME

CITY

STATE

COUNTRY

RULE-47

Kostoff, Ronald N.

Arlington

VA

US

US-CL-CURRENT: 707/1

Full Title Citation	Front Review Classification	Date Reference	Sequences	Attachments   Claims	KWIC Draw. De

2. Document ID: US 6886010 B2

L2: Entry 2 of 2

File: USPT

Apr 26, 2005

US-PAT-NO: 6886010

DOCUMENT-IDENTIFIER: US 6886010 B2

TITLE: Method for data and text mining and literature-based discovery

DATE-ISSUED: April 26, 2005

INVENTOR-INFORMATION:

NAME

CITY

STATE

ZIP CODE

COUNTRY

Kostoff; Ronald N.

Arlington

VA

US-CL-CURRENT: <u>707/3; 707/10, 707/4, 707/6</u>

Full Title Chation Front Review Classification Date Reference

Claims RWC Draw De

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